

# Design of a monolithic digital SiPM-IC in 150-nm CMOS technology

In house-design

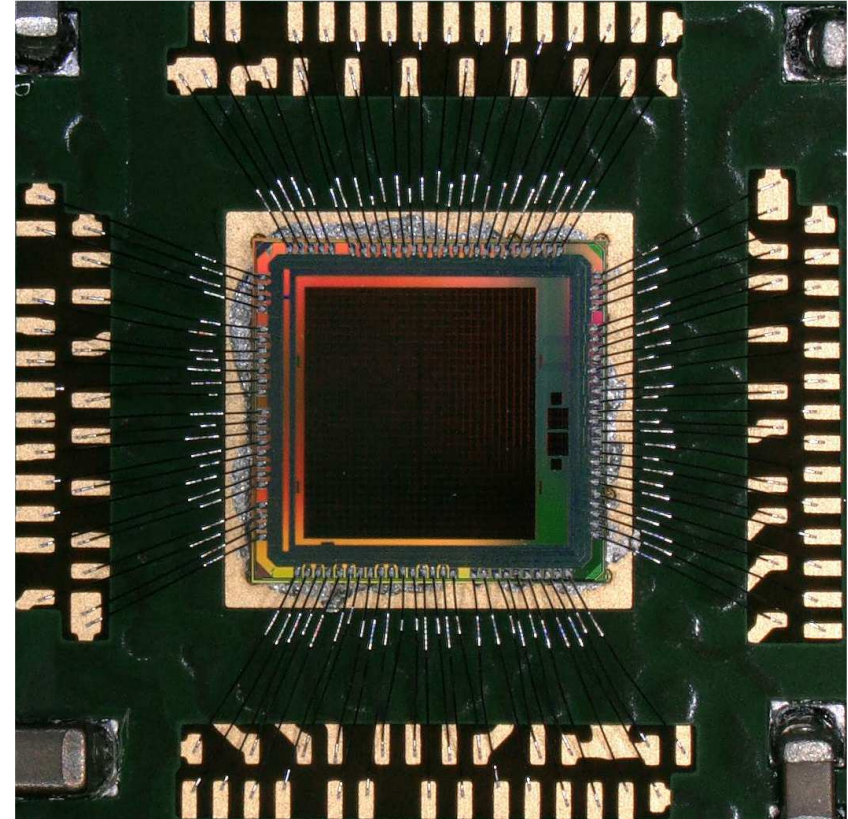
Presentation for the retreat of the detector platform

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# Outline

- Introduction to Silicon photomultipliers
  - What are SiPMs?
  - Why going to „digital“?
- DESY's 32-by-32-pixel digital SiPM-IC
  - Features
  - Circuit blocks description and characterization
- Lab measurements
  - With Caribou DAQ system
  - With laser source
  - In dark environment
- Conclusion

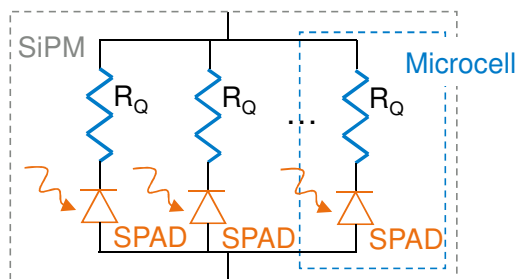


# Silicon photomultipliers (SiPM)

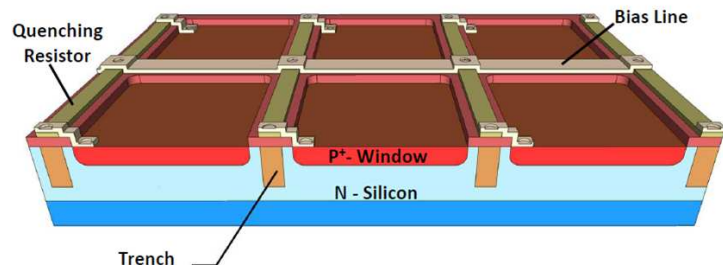
## What are SiPMs?

- SiPMs are solid-state single-photon-sensitive devices based on single-photon avalanche diodes (SPADs) implemented on common silicon substrate.
- Each SPAD is biased above breakdown voltage and operates in Geiger mode with typical gain of  $10^5$  to  $10^6$ .

## Analog SiPM



Section of KETEK SiPM Microcell



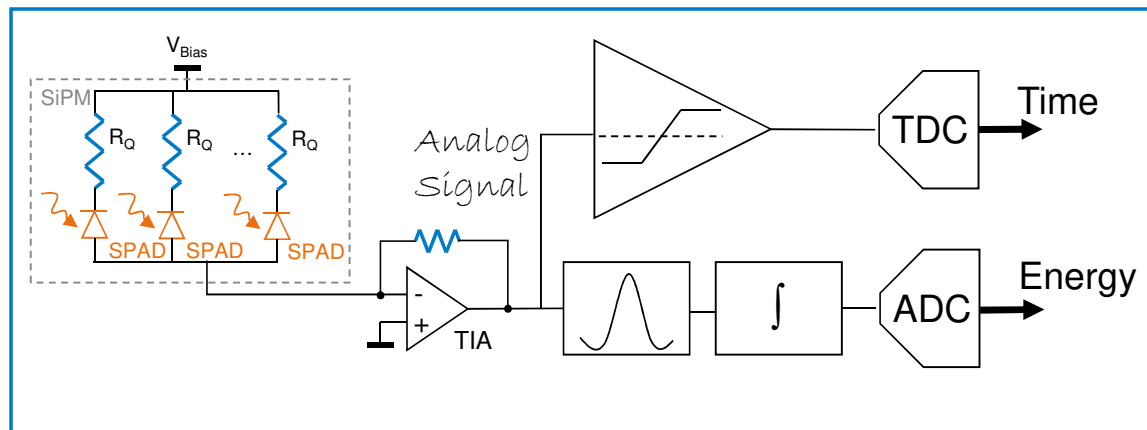
- Arrays of many SPADs, each one with its integrated passive-quenching resistor, labeled as microcells
- All microcells connected in parallel to a common anode and cathode
- The output current of the SiPM is the sum of all the cells, giving a signal proportional to the number of detected photons.

# SiPMs

## Digital SiPMs

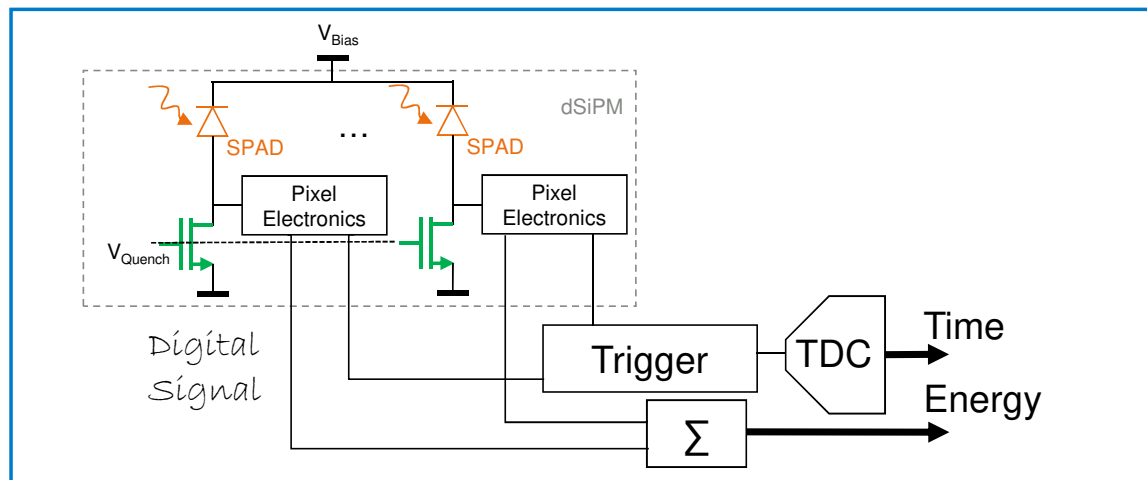
### Challenges of “classical” analog SiPMs

- Analog output requires digitization in electronics
- Often sizeable noise rates (typically kHz/mm<sup>2</sup>)
  - Very often dominated by a few pixels
- No information which pixel was hit



### Possible solution: Digital SiPMs

- Take advantage of SiPMs digital nature
  - Small quenching circuitry
  - Inverter as event discriminator
- Photon or hit counter, within pixel possible
- Possibility to switch off noisy pixel
- Hit map readout



# 32-by-32-pixel digital SiPM-IC

## Overview

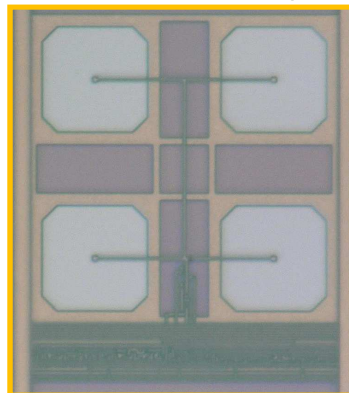
### Layout

- 32 x 32 pixels (1 pixel = 4 SPADs)
- In LFoundry's 150-nm CMOS technology
- 70- $\mu\text{m}$  pitch

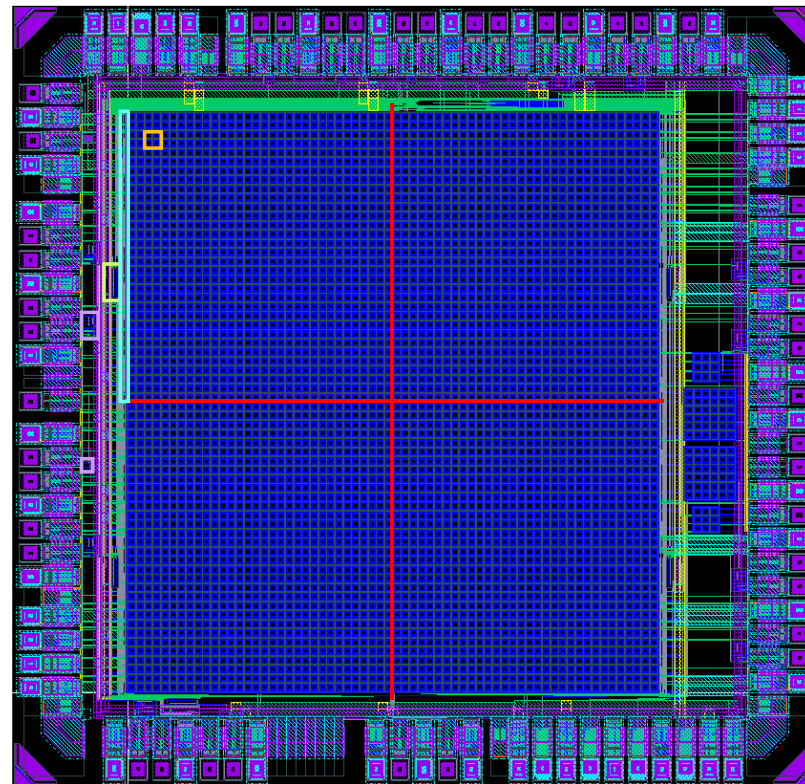
### Features

- Full hit matrix readout
- Pixel masking
- Time stamping per quadrant
  - 12-bit TDCs with <100-ps timing resolution
  - Validation logic with adjustable settings
- 1-Gbps LVDS links

69.6 x 76  $\mu\text{m}^2$



ca. 3400 x 3300  $\mu\text{m}^2$

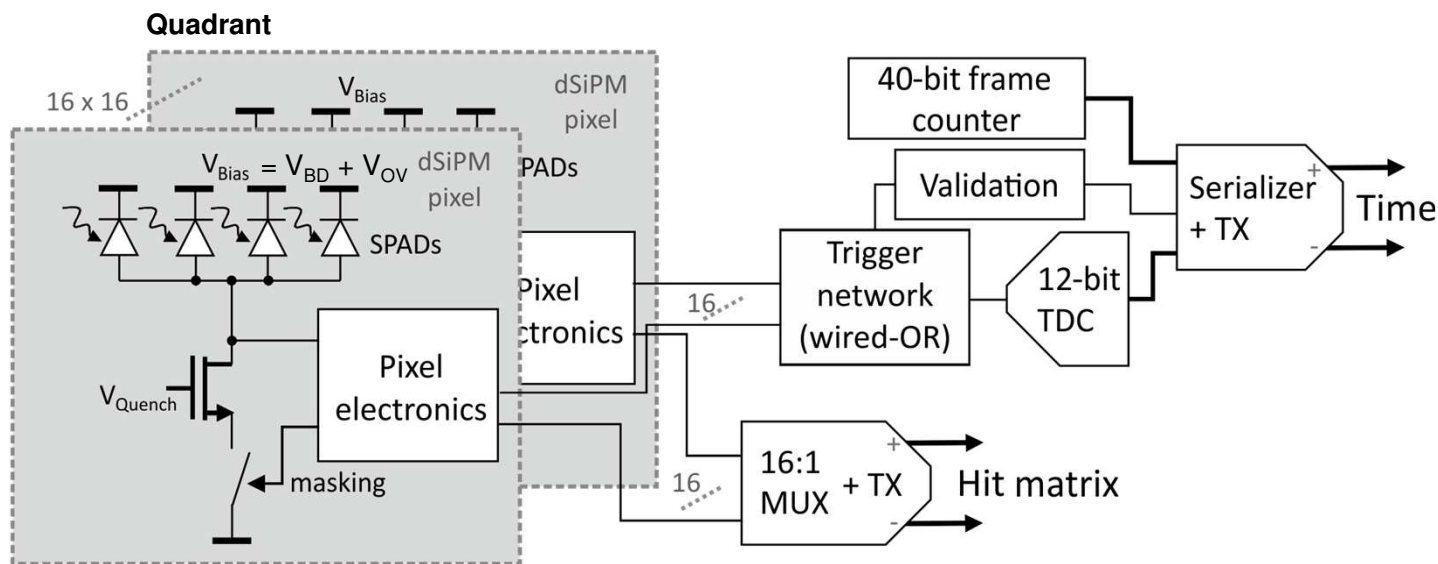


# 32-by-32-pixel digital SiPM-IC

## Quadrant block scheme

### The IC is divided into four quadrants

- Outputs of all pixels are combined in a wired-OR
- Fastest pixel signal triggers a running 12-bit TDC
- Validation logic to discard undesirable events
- Hit matrix is readout via a 16-to-1 multiplexer
- Frame-based readout



#### dSiPM pixel electronics

- Common readout of 4 SPADs
- 3.3-V NMOS transistor front end allowing an overvoltage of max. 3.6 V
- Quenching performed by a globally biased transistor
- Inverter as comparator stage for digital pulse shaping
- SRAM cell for masking
- Deadtime: min. 25 ns
- Power: 10  $\mu$ W
- Area: 400  $\mu$ m<sup>2</sup>

#### Data rates @ 3-MHz frame clock

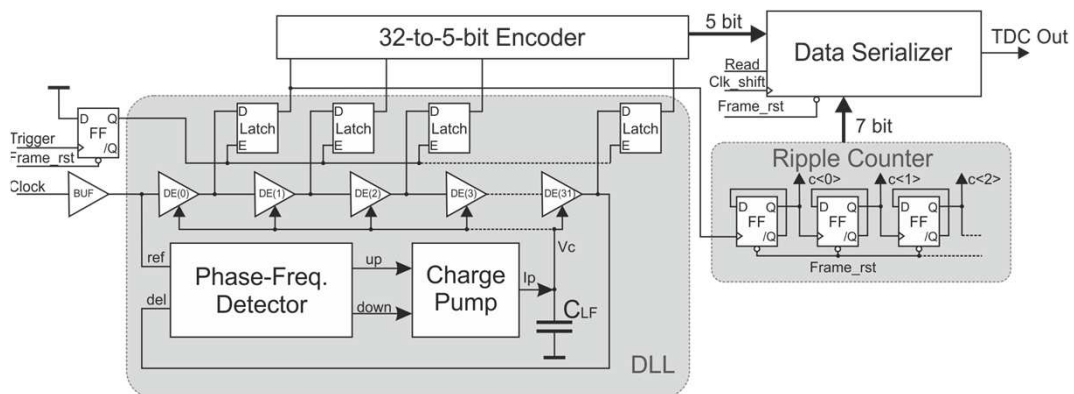
- Hit data: 4 \* 816 Mbps
- Timing data: 408 Mbps
- Total sustained data throughput of 4 Gbit/s @ 3-MHz frame rate



# 32-by-32-pixel digital SiPM-IC

## Circuit blocks:

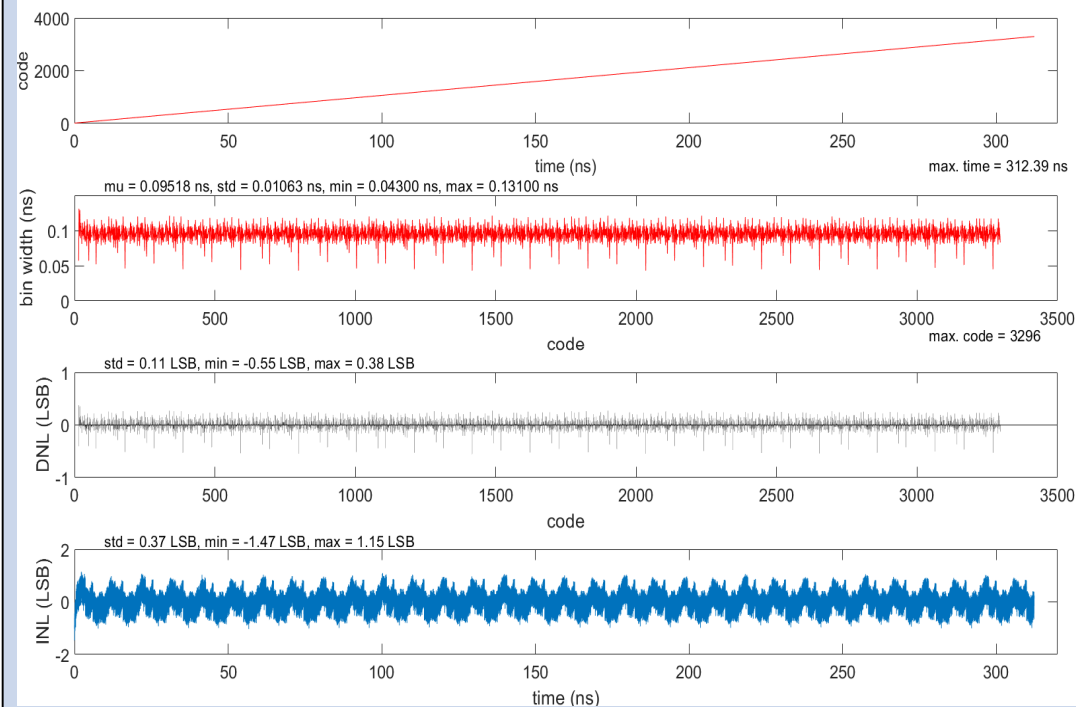
### Time-to-digital converter



#### @408 MHz reference clock

- Time resolution: 95.8 ps,  $\sigma = 13.65$  ps
- Bit resolution: 11.67 bit
- Dynamic range: 314 ns
- Max DNL = -0.74/0.35 LSB
- Max INL = -1.43/1.39 LSB
- Power: 11 mW @1.8 V
- Area: 78 x 157  $\mu\text{m}^2$

### TDC characterization – on separate test circuit of one sample

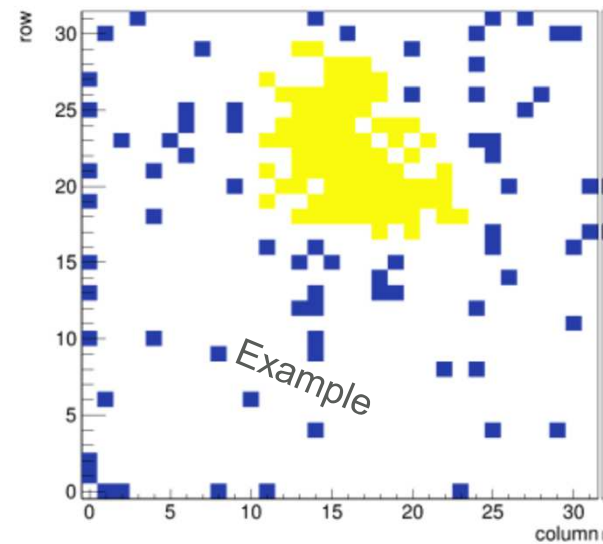
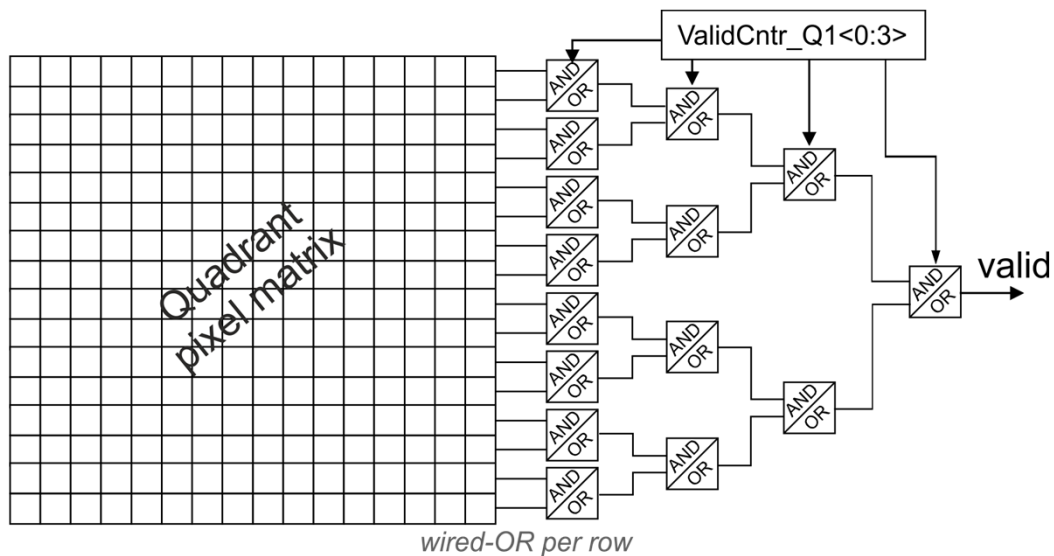


- Trigger input with step size of 1 ps over entire dynamic range
- Bin width: width of each step  $\rightarrow$  time-stamp signal
- DNL: deviation of each bin width to the average value
- INL: deviation to an ideal line fitted into the step curve

# 32-by-32-pixel digital SiPM-IC

## Circuit blocks:

### Validation logic



### Event validation

- Four steps
- With each step AND/OR gate configurable
- For cluster identification of simultaneously fired pixel
- For discarding undesirable events

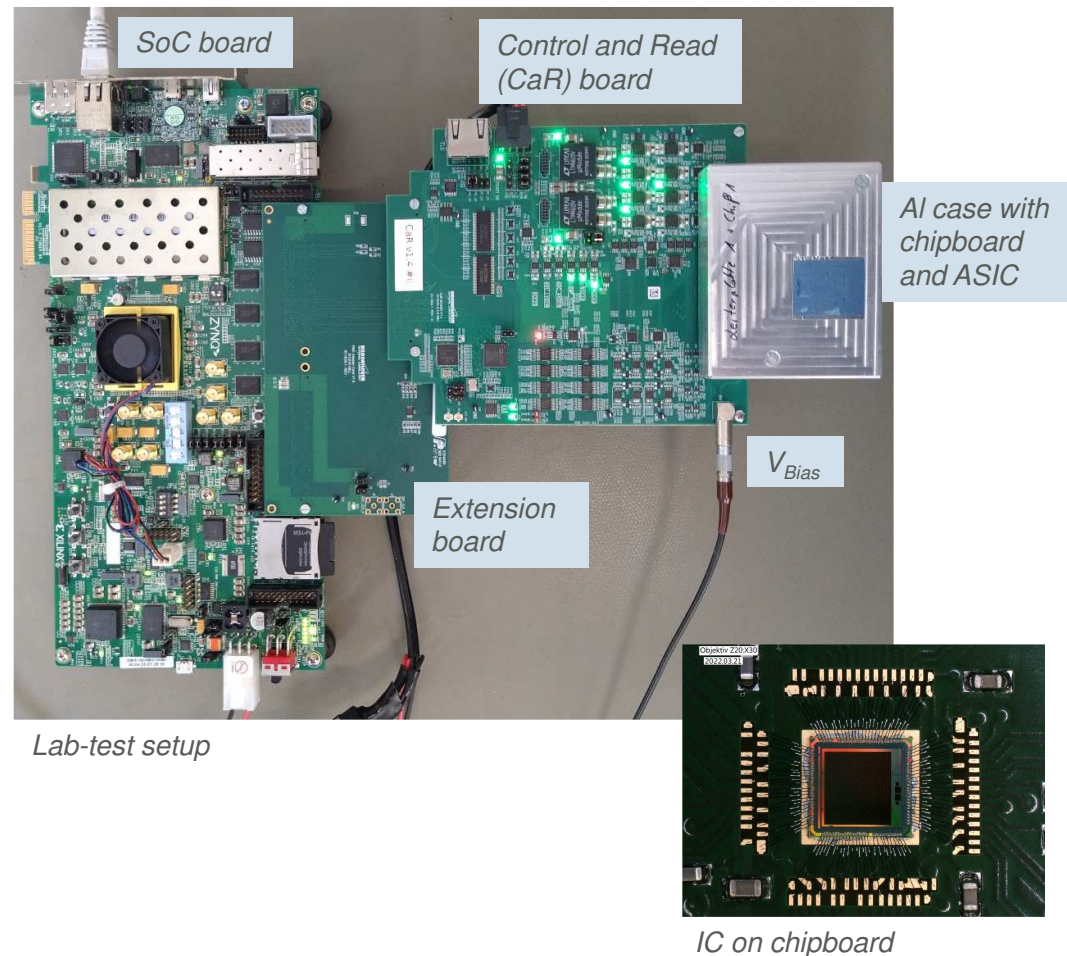


# Measurements – in lab

## With Caribou DAQ system

- A versatile readout system developed by CERN, BNL, and DESY
- For fast and simple implementation of new detectors
- System on Chip (SoC) Board – CPU and FPGA on same die
  - A CPU runs DAQ and control software
  - An FPGA runs custom hardware for data handling and detector control
- Control and Readout (CaR) Interface Board
  - Physical interface from the SoC to the sensor
  - Peripherals needed to interface and run the chip: power supplies, ADCs, voltage/current references, LVDS links, etc.
- Chip Board – passive & detector-specific components

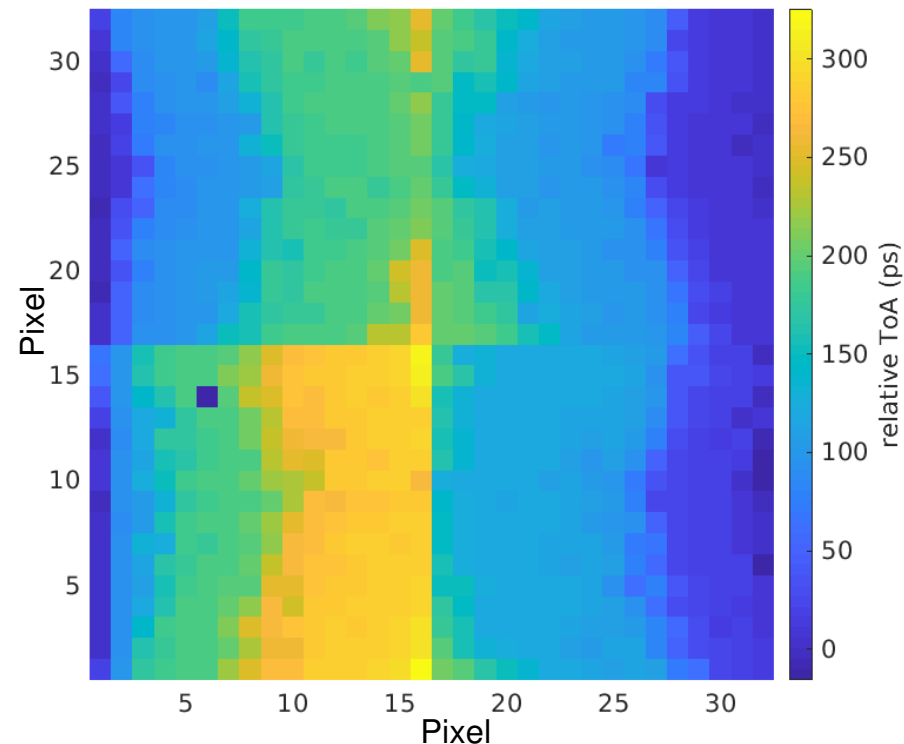
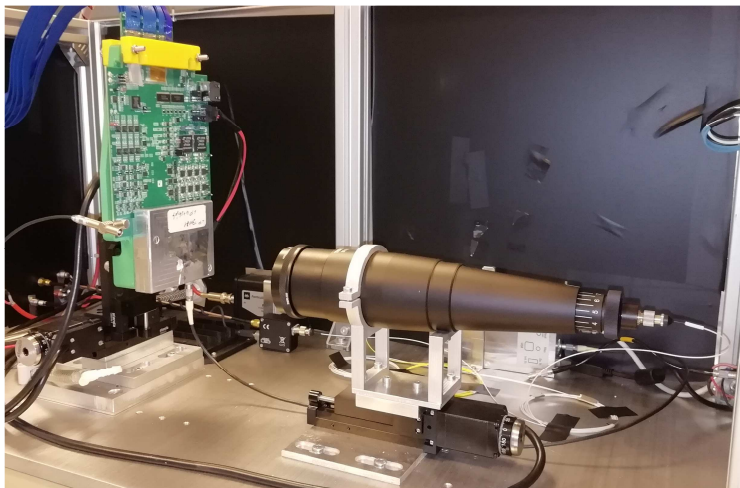
<https://doi.org/10.22323/1.370.0100>



# Measurements – in lab

## Propagation delays

- DUT placed on a x-y stage, laser optical system on a z-stage
- 1054 nm pulsed laser, in sync. with the DAQ clock
- Scan chip pixel-by-pixel
  - Only one pixel enabled and directly illuminated
  - Laser spot diameter of  $\sim 0.5$  mm
  - ToA store
  - Relative ToA =  $\text{ToA}_{\text{pixel}} - \text{ToA}_{\text{pixel close to TDC}}$



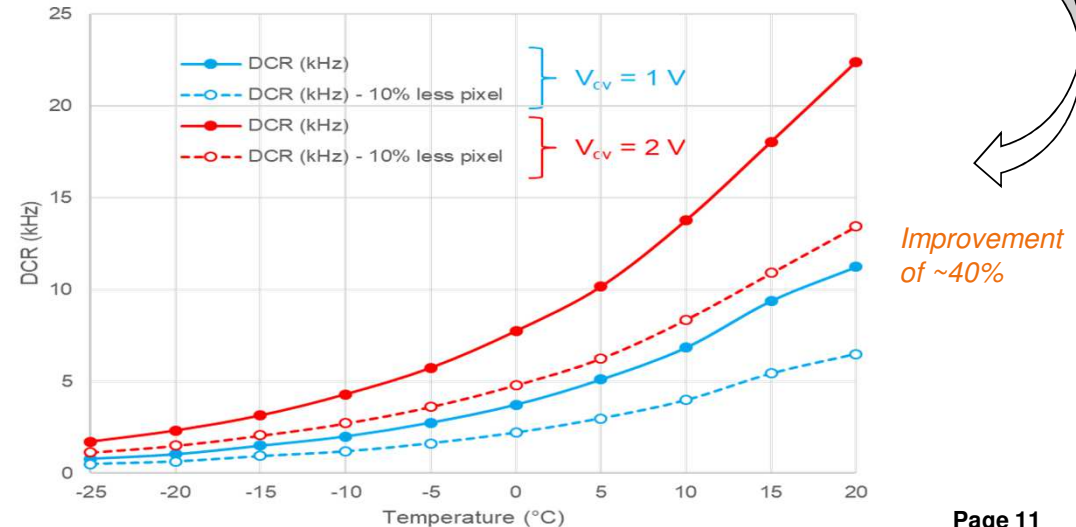
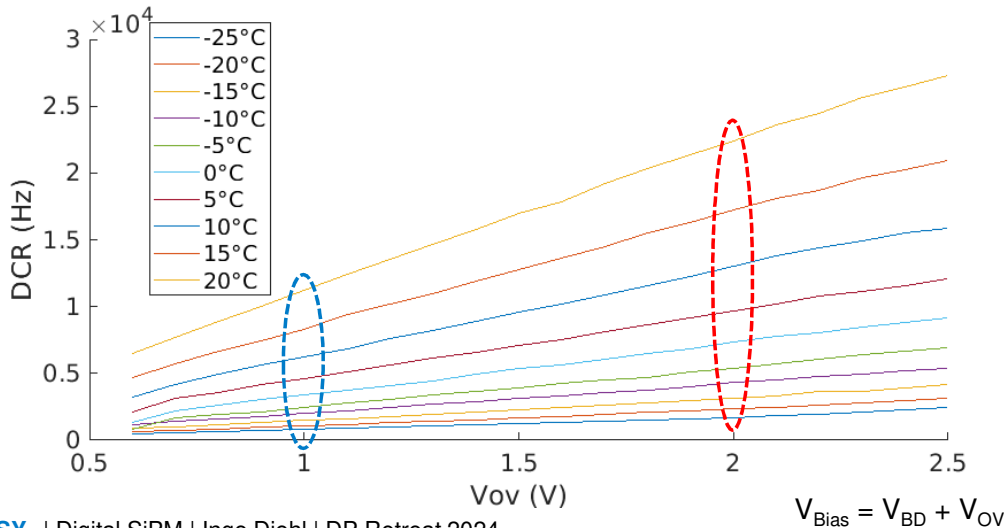
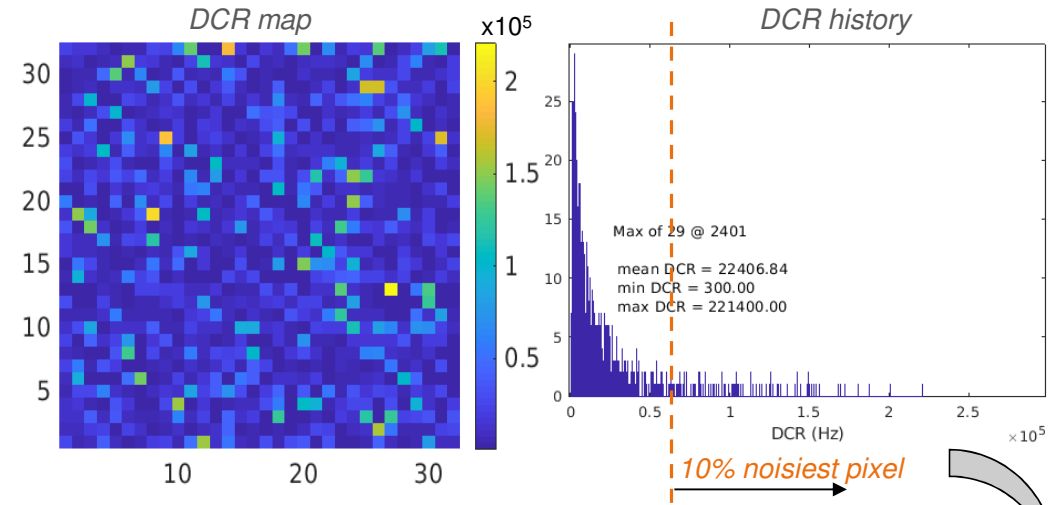
- Clear function of distance to each TDC
- Max.  $\sim 326 \text{ ps} \pm 86 \text{ ps}$

*see Daniil's talk: "TCT box: laser box as a user facility"*

# Measurements – in lab

## Dark-count rates

- Thermal generated events in dark conditions
- Strong dependence on temperature and overvoltage
- Dominated by some noisy pixels
  - Pixel masking helps!
- DCR differs from sample to sample, ~25 kHz per pixel at 20°C and  $V_{ov} = 2$  V without masked pixels



# Conclusion and outlook

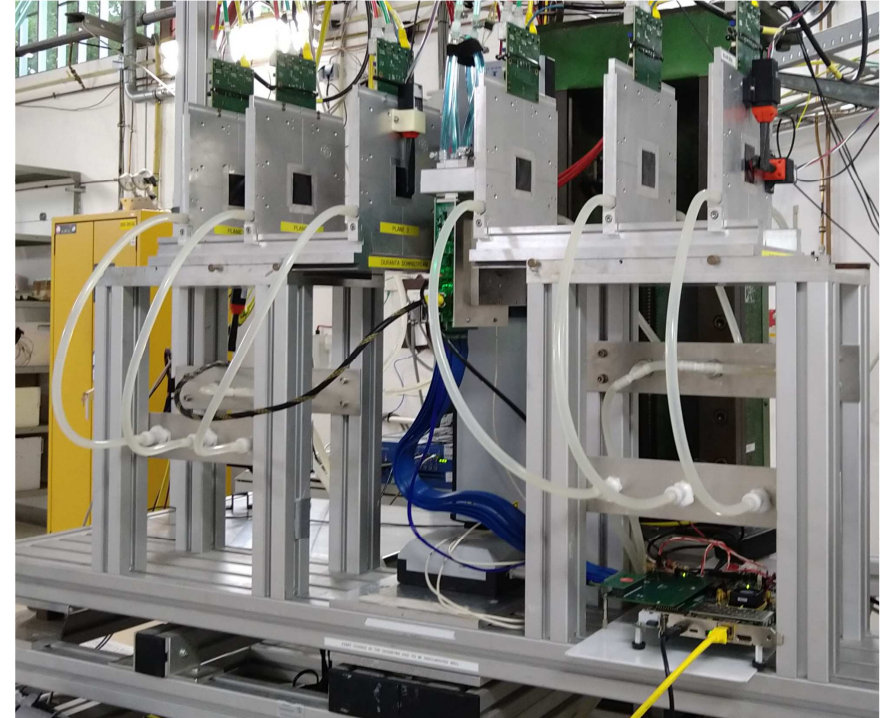
## DESY's digital SiPM-IC

- Proof-of-principle:
  - Successfully demonstrated
  - Process limitations identified
  - Full detector system can be used
    - E.g. in test beam

*see Gianpiero's talk: "Test beam-characterization of DESY's digital SiPM-IC"*
- Possible improvements:
  - Masking of individual SPAD instead of entire pixel
  - LF 110 CIS → DCR reduction
  - Customized SPAD cell → fill factor reduction
  - Multi-layer arrangements → DCR reduction, tracking, ...

### Infos:

- <https://doi.org/10.1088/1748-0221/19/01/P01020>
- <https://indico.cern.ch/event/1184921/contributions/5576923/>



# Thank you.

Test beam results are coming soon. 😊

## Contact

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